

#### **IEC QUALITY ASSESSMENT SYSTEM (IECQ)**

covering Electronic Components, Assemblies, Related Materials and Processes

For rules and details of the IECQ visit www.iecq.org

## Schedule of Scope to Certificate of Approval

**Independent Testing Laboratory** 

IECQ Certificate No.: IECQ-L ULTW 21.0003
CB Certificate No.: 50600408 ITL

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Schedule Number: IECQ-L ULTW 21.0003-S Rev No.: 3 Revision Date: 2023/08/10 Page 1 of 2

## Appendix-1 (50600408 ITL) Schedule of Scope to Certificate of Approval

Test Technology 測試項目	Test Method 測試標準	
Electrostatic Discharge (ESD) Test - Human Body Model (HBM)	ANSI/ESDA/JEDEC JS-001; AEC-Q100-002;	
人体模型静电敏感度试验	MIL-STD-883L-2017 method 3015.9;	
	AEC-Q101-001; GJB 548B-2005 方法 3015。	
Electrostatic Discharge (ESD) Test	ANSI/ESDA/JEDEC JS-002;	
- Charged Device Model (CDM) 充电器件模型静电敏感度试验	AEC-Q100-011; AEC-Q101-005。	
Latch-Up Test	JEDEC JESD78F;	
集成电路闩锁	AEC-Q100-004 ·	
3D Optical Microscope (3D OM) 3 维数字光学显微镜	SHJF-WI-FA-031	
X-RAY microscope X-射线显微镜	SHJF-WI-FA-005	
Laser 镭射	SHJF-WI-FA-007	
InGaAs microscope 砷化镓微光显微镜	SHJF-WI-FA-019	
Optical Beam Induced Resistance Change (OBIRCH) 镭射加热扫描定位	SHJF-WI-FA-012	
IV cure tracer	SHJF-WI-FA-010	
曲线追踪仪测试	SHUF-WI-FA-UIU	

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Probe 射频探针	SHJF-WI-	FA-014	
Reactive-Ion Etching RIE 气体蚀刻	SHJF-WI-	FA-022	
Grinder 研磨	SHJF-WI-	FA-024	
Secondary Electron Microscope (SEM) 扫描电镜-8100	SHJF-WI-	FA-025	
Focused Ion beam (FIB) 聚焦离子束线路修补-CKT	SHJF-WI-	FA-029	
Dual Beam Focused Ion beam (Dual Beam FIB) 双束离子	SHJF-WI-	FA-027	

Technical Reviewer of DQS: Michael Chou Date: 8/10/2023

